



Control System of Cryomodule Test Facilities for SHINE

H.Y. Wang, G.H. Chen, J.F. Chen, J.G. Ding,
M. Li, Y.J. Liu, Q.R. Mi, H.F. Miao, C.L. Yu

Shanghai Advanced Research Institute
Chinese Academy of Sciences

SHINE



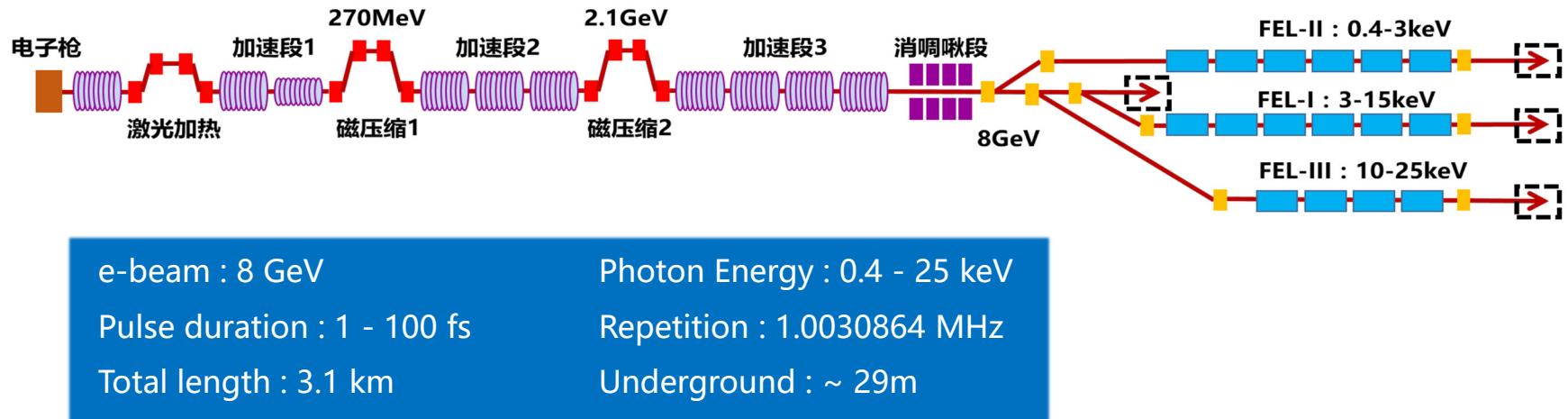
Outline

- SHINE Project Introduce
- Cryomodule Test Facilities
- Control System
 - Temperature
 - Pressure
 - Cryogenic Valve
 - Liquid Level
 - Heater Power
 - Vacuum
 - Functional Safety
 - IOC, OPI, AA
- Conclusion



SHINE Project

- Shanghai HighRepetition-Rate XFEL and Extreme Light Facility (SHINE)
- First hard X-ray FEL facility in China

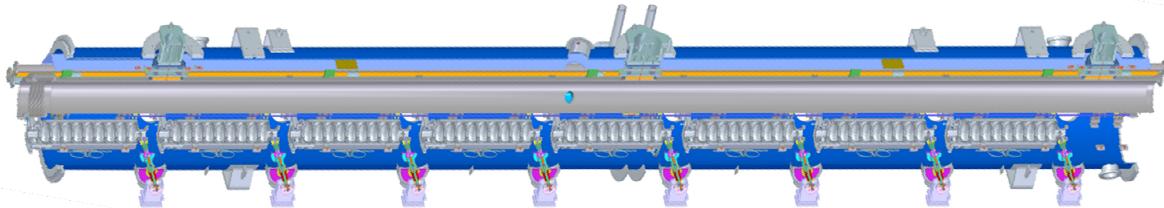




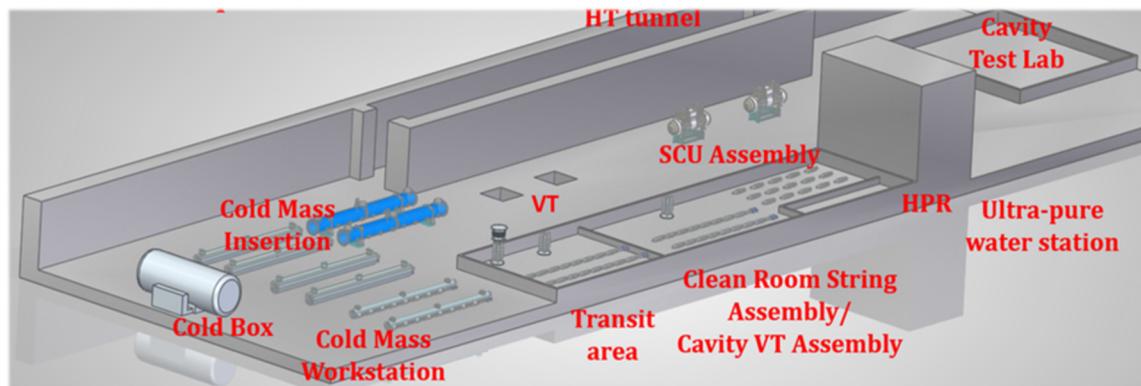
Cryomodule Test Facilities



- 1.3GHz Cryomodules (75)
- 3.9GHz Cryomodules (2)

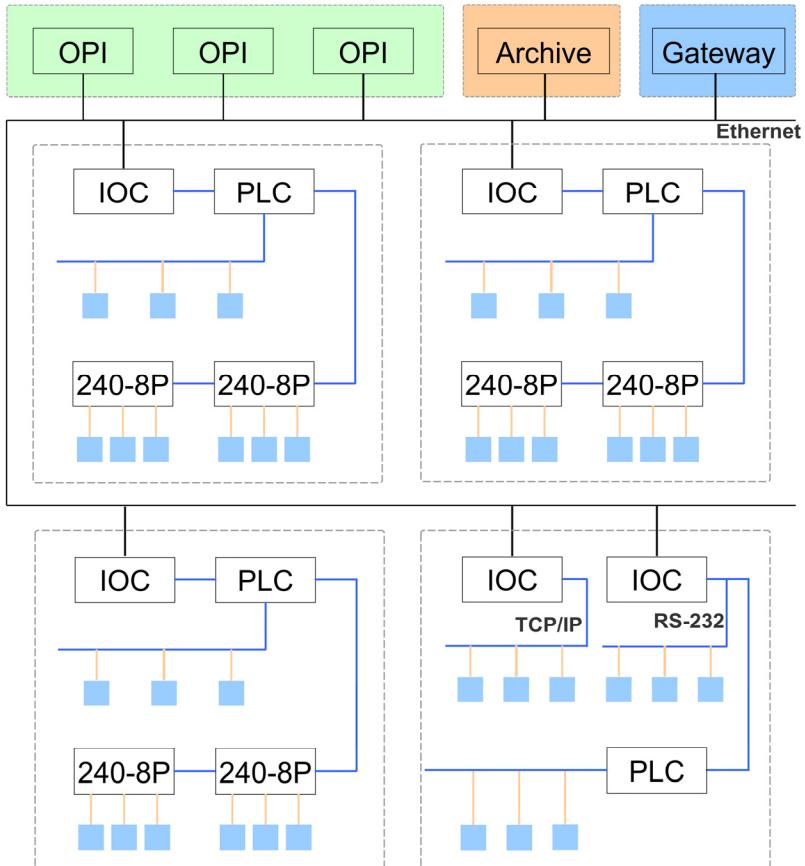


- Cryogenic component multi-functional test facility (1)
- Superconducting cavity vertical test facility (2)
- Superconducting cavity horizontal test facility (2)



Crontrol System

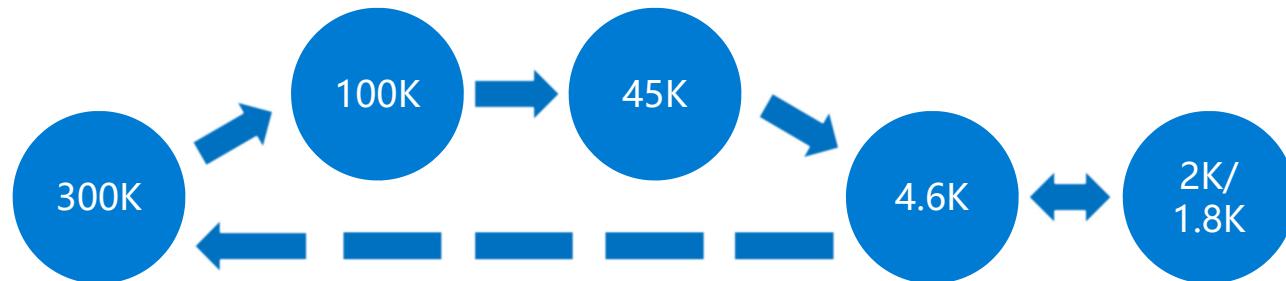
- The control system will provide operators and engineers with a comprehensive and easy-to-use tool to control and monitor the components.
- Device control : pressure, temperature, liquid level, cryogenic valve, vacuum signal, etc.
- Integration : control network, server cluster, data storage, user interface, high level software and central control room.





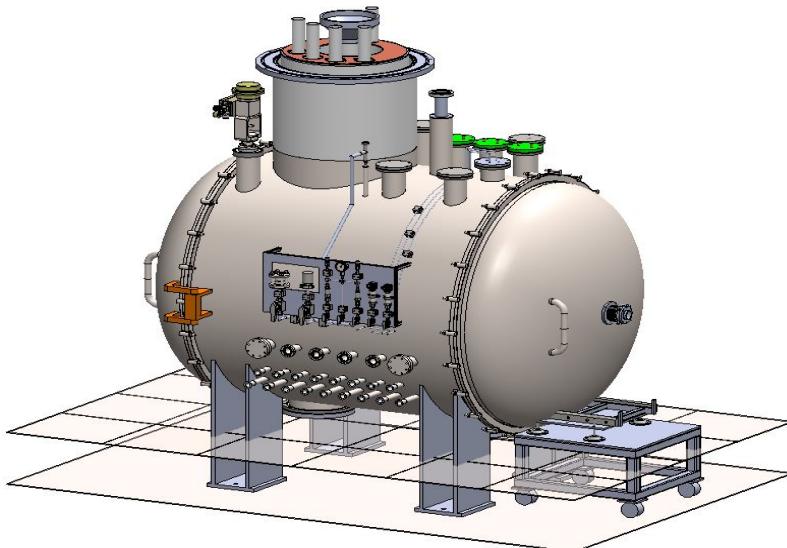
Crontrol System

- Monitor and control the pressure, temperature, liquid level, vacuum signal, etc.
- Adjust the heater power according to the RF signal to stabilize the load of the cryomodule.
- Adjust the J-T valve opening through stabilizing the liquid helium level.
- Manual or automatic control the cryogenic valve for different processes.
- Functional safety systems, including the signal of cryogenic factory and LLRF.
- Data exchange with the cryogenic factory control system.





Multi-functional test facility



Superconducting Magnets



Coupler



Cold-BPM

Signal	Qty	I/O	Type
Temperature	24	Input	CX-1030-CU-HT
Pressure	5	Input	Analog
Liquid Level	1	Input	Analog
Cryogenic valve	2	Input	Analog
Cryogenic valve	2	Output	Analog, PID
Interlock	4	Input/Output	Digital
Heater Power Supply	4	Input/Output	Analog, Digital
Vacuum Gauge	6	Input	Serial port

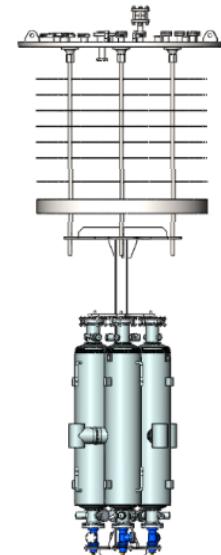


Vertical Test facility

Signal	Qty	I/O	Type
Temperature	47	Input	CX-1030-CU-HT
Pressure	5	Input	Analog
Liquid Level	1	Input	Analog
Cryogenic valve	4	Input	Analog
Cryogenic valve	4	Output	Analog, PID
Interlock	4	Input/Output	Digital
Heater Power Supply	16	Input/Output	Analog, Digital
Vacuum Gauge	6	Input	Serial port



1 Cavity



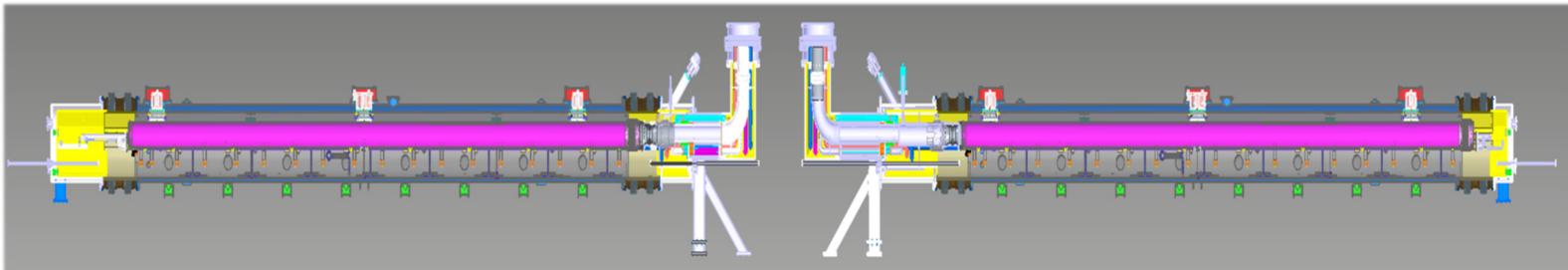
4 Cavities



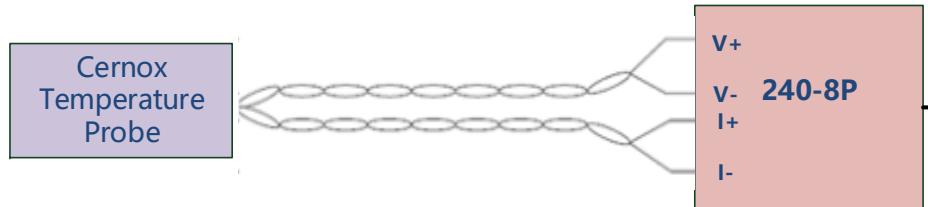
Horizontal Test facility

- Facility 1
 - prototype cryomodules
 - mass production cryomodules
- Facility 2
 - mass production cryomodules

Signal	Qty	I/O	Type
Temperature	120	Input	CX-1030-CU-HT
Pressure	2	Input	Analog
Liquid Level	3	Input	Analog
Cryogenic valve	4	Input	Analog
Cryogenic valve	4	Output	Analog, PID
Interlock	14	Input/Output	Digital
Heater Power Supply	16	Input/Output	Analog, Digital
Vacuum Gauge	3	Input	Serial port
Ion Pump	3	Input	Serial port
Magnet Power Supply	3	Input	Ethernet



Temperature

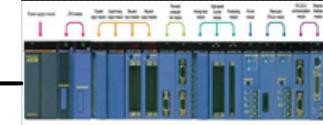


LakeShore Model 240-8P Cryogenic temperature input module
8 inputs compatible with both resistive and diode temperature devices

PROFIBUS-DP network communications

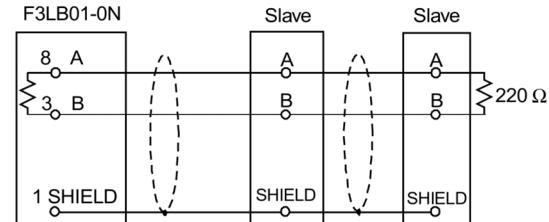


PROFIBUS



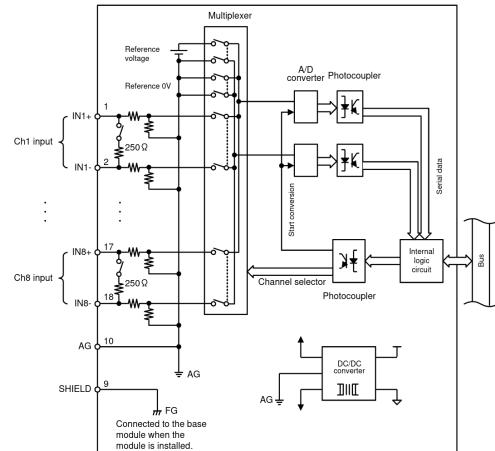
Yokogawa PLC

PROFIBUS-DP master
control and
communicate with the
sensors.



Pressure

- KELLER PAA-41X
 - 0...100mbar
- KELLER PAA-33X
 - 0...1600mbar
 - 0...3000mbar
- F3AD08-4R
 - 8 channels
 - 4-20mA



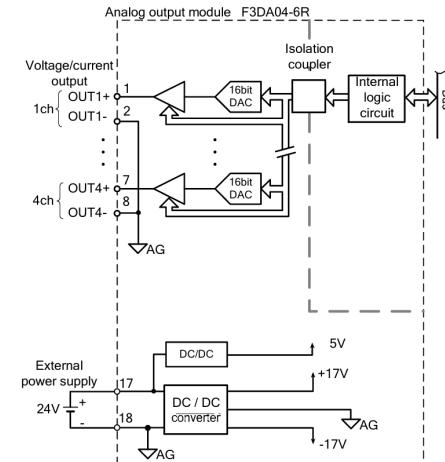
Cryogenic Valve

- Toko Valex T-8800



- Electropneumatic Positioner
 - SAMSON 3730-2

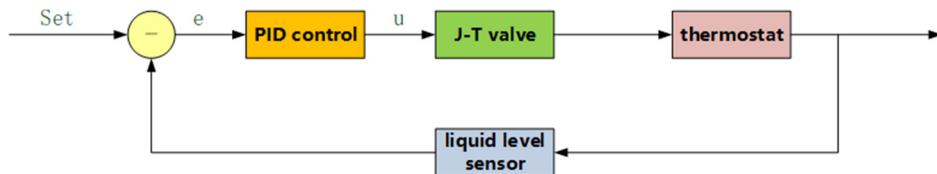
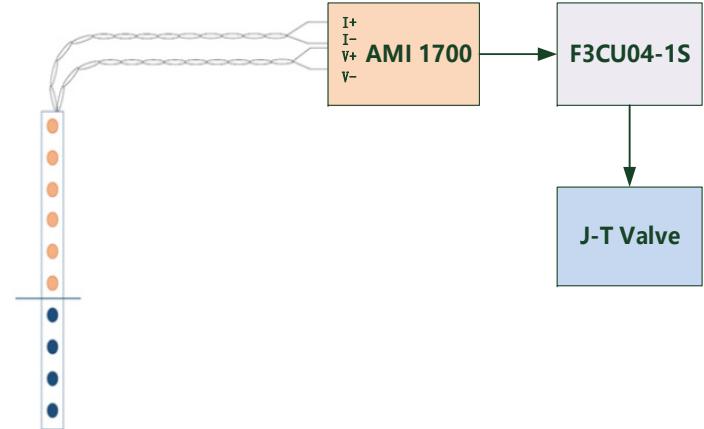
- F3AD08-4R
- F3DA04-6R





Liquid Level

- Liquid level monitor and stability control
- AMI 2K level probe
- AMI 1700-2K level gauge
- Yokogawa F3CU04-1S PID module
- Manual control the cryogenic valve opening
- PID closed-loop control of the 2K liquid helium level



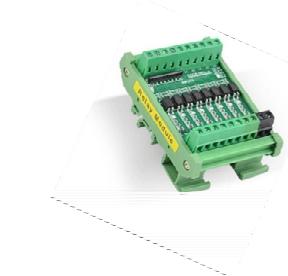
$$u(t) = K_P [e(t) + \frac{1}{T_I} \int_{s=0}^t e(s) ds + T_D \frac{d(e(t))}{dt}]$$



Heater Power

- Cryomodule heating and compensation of total thermal load power
- Heater : Omega KH-112/10 50W
- Power supply : TDK Z60-3.5-C
- Yokogawa PLC
 - F3XD16-3F, digital input, power supply status
 - F3YC08-0C, relay output, power supply control
 - F3AD08-5R, analog input, current readback
 - F3DA08-5R, analog output, current setting
- Manually control the heater current
- Closed-loop control of the total thermal load power

Cavity dynamic load
+
Heater Power
||
Cryomodule Total Power
(constant)



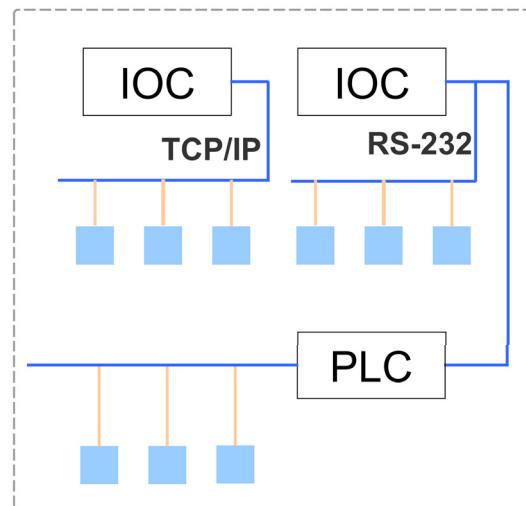


Magnet PS

Vacuum

- Superconducting Magnet
- SSRF power supply controllers
- EPICS streamDevice/asynDriver IOC
 - Power switch control
 - Load current monitor
 - Reference current monitor
 - Current slope control
 - Power supply status monitor

- Agilent XGS600 gauge controller
- Zhenghua gauge controllers
- Zhenghua ion pump power controllers
- EPICS streamDevice/asynDriver IOC





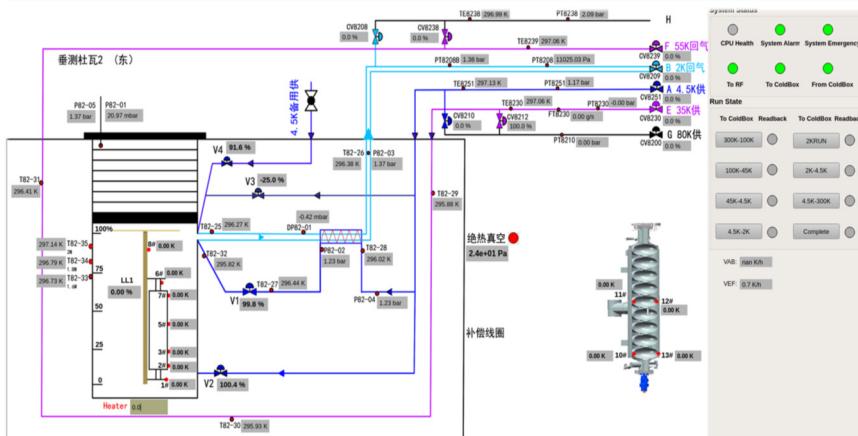
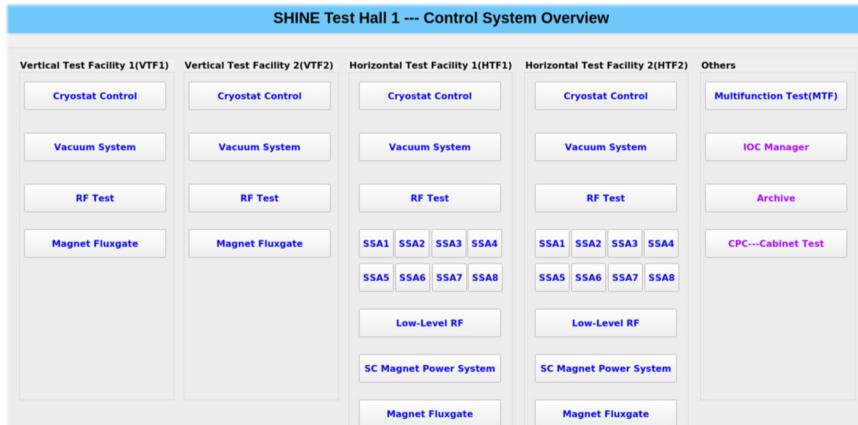
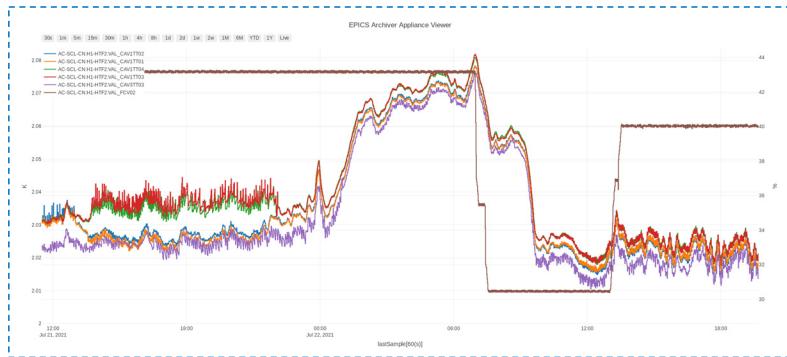
Functional Safety

- Protect the important components of the facility
- Report the fault information to the control system
- Latch: save the signal alarm state
- Reset: release the alarm latch
- Bypass: temporarily release the interlock response to the signal from the software

	Real value(Pa)	Setting(Pa)	Alarm	Bypass	Latched	Reset
VAC01: (Cryostat)	0.0e+00 Pascal		●	Bypassed	●	Reset
VAC02: (Beam)	0.0e+00 Pascal		●	Not Bypassed	●	Reset
VAC03: (Coupler)	0.0e+00 Pascal		●	Not Bypassed	●	Reset
PT01:	-1.75100 bar	1.5	●	Not Bypassed	●	Reset
CP1TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP2TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP3TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP4TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP5TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP6TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP7TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
CP8TT02:	0.000 K	300.0	●	Not Bypassed	●	Reset
From ColdBox:			●	Not Bypassed	●	Reset
LT02:			●	Not Bypassed	●	Reset

IOC - OPI - AA

- IOC: MOXA DA-682B
 - OPI: PyDM
 - Archive Appliance



SHINE



Conclusion

- Multiple facilities have been built for SHINE cryomodule and superconducting cavity test.
- The local control systems are all based on Yokogawa PLC, which monitors and controls the process variables such as temperature, pressure, liquid level and power of the heater.
- PID and other algorithms are used to keep liquid level and power balanced.
- EPICS is adopted to integrate these facilities along with vacuum devices, solid state amplifiers, LLRF and RF measurement system, etc.
- The system development and debugging have been completed, and it has operated stably for several months.



Thanks for your attention !